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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM FILING DATE CLASS SUBCLASS GAU EXAMINER
10021608 12/11/2001 438 217 2842 Li, Ng...

**APPLICANTS: Lim Jong-Kill;

**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:
REPUBLIC OF KOREA 2001-1255 01/10/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

5484-85

TITLE : Exposure control apparatus in a lithography system and method thereof

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

| NOTICE OF ALLOWANCE MAILED | | Assistant Examiner | CLAIMS ALLOWED | |
|---|-----------|--------------------|----------------------|----------------------|
| | | | Total Claims | Print Claim for O.G. |
| ISSUE FEE | | Primary Examiner | DRAWING | |
| Amount Due | Date Paid | | Sheets Drwg. | Figs. Drwg. |
| <input type="checkbox"/> TERMINAL DISCLAIMER | | PREPARED FOR ISSUE | Application Examiner | |
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